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256

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10045412	FILING DATE 01/12/2002	CLASS 257	SUBCLASS 138	GAU 2844	EXAMINER Stafira
**APPLICANTS: Hu Clark; Jeng Hendrix; Jang Bor Ping; 356					
**CONTINUING DATA VERIFIED:					
<p>BEST AVAILABLE COPY</p>					
** FOREIGN APPLICATIONS VERIFIED:					
PG-PUB <input type="checkbox"/>		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed		<input type="checkbox"/> yes <input checked="" type="checkbox"/> no		ATTORNEY DOCKET NO 67,200-655	
35 USC 119 conditions met		<input type="checkbox"/> yes <input checked="" type="checkbox"/> no			
Verified and Acknowledged Examiners's initials <i>ND</i>					
TITLE : Semiconductor wafer tilt monitoring on semiconductor fabrication equipment plate					
U.S. DEPT. OF COMM./PAT. & TM-PTO-436L (Rev. 12-94)					

NOTICE OF ALLOWANCE MAILED		Assistant Examiner		CLAIMS ALLOWED	
				Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner		DRAWING	
Amount Due	Date Paid			Sheets Drwg.	Figs. Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE		Application Examiner	
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